AMENDMENTS TO THE CLAIMS

1 to 8. (Canceled)

9. (New) A photosensitive resin composition comprising:

a multi-functional bisphenol A novolak epoxy resin, a functionality of which is 5-functional groups or more and represented by general formula (3) shown below:

(in the formula, R_1 to R_6 are independently H or CH_3 , respectively, n indicates zero or larger integer); and

a cation polymerization initiator represented by general formula (1) shown below:

(in the formula, X_1 and X_2 indicate a hydrogen atom, a halogen atom, a hydrocarbon group which may contain an oxygen atom or a halogen atom, or an alkoxy group to which a substituent may bond, respectively, and they may be identical to or different from one another, and Y indicates a hydrogen atom, a halogen atom, a hydrocarbon group which may contain an oxygen atom or a halogen atom, or an alkoxy group to which a substituent may bond).

10. (New) The photosensitive resin composition according to claim 9, wherein the cation polymerization initiator is a compound represented by chemical formula (2) shown below:

11. (New) The photosensitive resin composition according to claim 9, further comprising a linear polymeric 2-functional epoxy resin.

12. (New) The photosensitive resin composition according to claim 9, further comprising a naphthol sensitizer.

13. (New) The photosensitive resin composition according to claim 9, further comprising γ -butyrolactone.

14. (New) A photosensitive resin composition laminate comprising:

a photosensitive resin composition layer obtained from the photosensitive resin composition according to clam 9; and

a protective film,

wherein at least one side of the photosensitive resin composition layer is protected with the protective film.

15. (New) A method of forming a pattern comprising the steps of:

applying the photosensitive resin composition according to claim 9 on a desired base and then drying the photosensitive resin composition;

exposing a radiation beam on a photosensitive resin composition layer to form given resin patterns;

developing the beam-exposed photosensitive resin composition layer; and heat-treating the resulting resin patterns to yield cured resin patterns of given shapes.

16. (New) A method of forming a pattern comprising the steps of:

peeling the protective film away from the photosensitive resin composition laminate according to claim 14;

attaching a resulting photosensitive resin composition layer on a desired base; exposing a radiation beam on the photosensitive resin composition layer to form a given pattern;

developing the beam-exposed photosensitive resin composition layer; and heat-treating the resulting resin patterns to yield cured resin patterns of given shapes.

17. (New) The photosensitive resin composition according to claim 9, wherein a content of the multi-functional bisphenol A novolak epoxy resin, a functionality of which is 5-functional groups or more is 80 to 99.9 mass% based on a solid content of the photosensitive resin composition.